Title (en)

METHOD OF PRODUCING A STRUCTURED SURFACE

Title (de)

VERFAHREN ZUR ERZEUGUNG EINER STRUKTURIERTEN OBERFLÄCHE

Title (fr)

PROCEDE DE PRODUCTION D'UNE SURFACE STRUCTUREE

Publication

EP 1088341 A2 20010404 (EN)

Application

EP 99922377 A 19990520

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Abstract (en)

[origin: WO9962106A2] Clusters of an etchable material such as silver are deposited on a silicon substrate (10) to form peaks (12). The peaks (12) are then at least partially etched away by plasma etching to form cones (14) or pillars of silicon on the substrate (10).

IPC 1-7

H01L 21/308; H01J 9/02

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